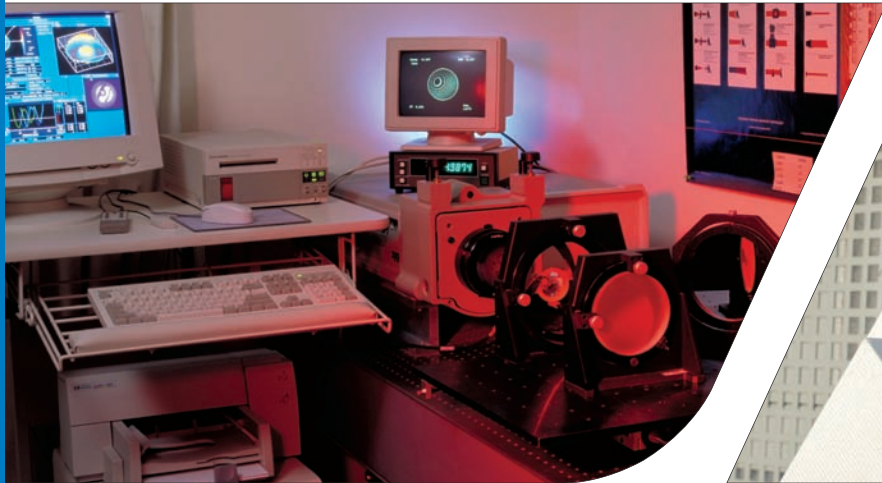


Optics | METROLOGY AND DESIGN



Extensive Metrology Capability

- White light interferometry
- Fizeau phase shift interferometers
 - Up to 12" capability
- Twyman-Green Laser phase shift interferometry with variable input wavelength
 - Allows for multi-wavelength interferometry at 20 different laser wavelengths
- Taylor Hobson® Profilometer
 - Resolution less than 1 nm
- Computer generated holograms (CGH) for cylindrical optics
- QED subaperture™ stitching
 - For production of high performance test optics
 - $\lambda/40$ for transmission and reference flats
 - $\lambda/30$ for spherical optics
- Spot size measurement
- Goniometric spectrophotometers
 - CVI Melles Griot offers analysis of reflectivity and transmission for a broad range of wavelengths
 - Direct reflection measurements from 190 nm to 1800 nm and 8.5° to 60°

Techniques

- Specialized anti-reflective coating measurement techniques
- Xsquared™ filter laser based metrology for high OD filters

Design

- Geometrical optical design software
 - Code V™
 - Zemax®
 - SYNOPSIS®
- Stray Light and Illumination
 - TracePro™
 - ProSource™
- Mechanical System Design
 - SolidWorks Simulation Professional™
 - AutoCad™
- Engineering
 - Expert, experienced team of engineers
- Thin Film Design Software
 - FilmStar
 - TFCalc
 - Essential McLeod
 - Optilayer

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